## Deformation mechanism of amorphous/nanocrystalline multilayers thin films on polyimide substrates

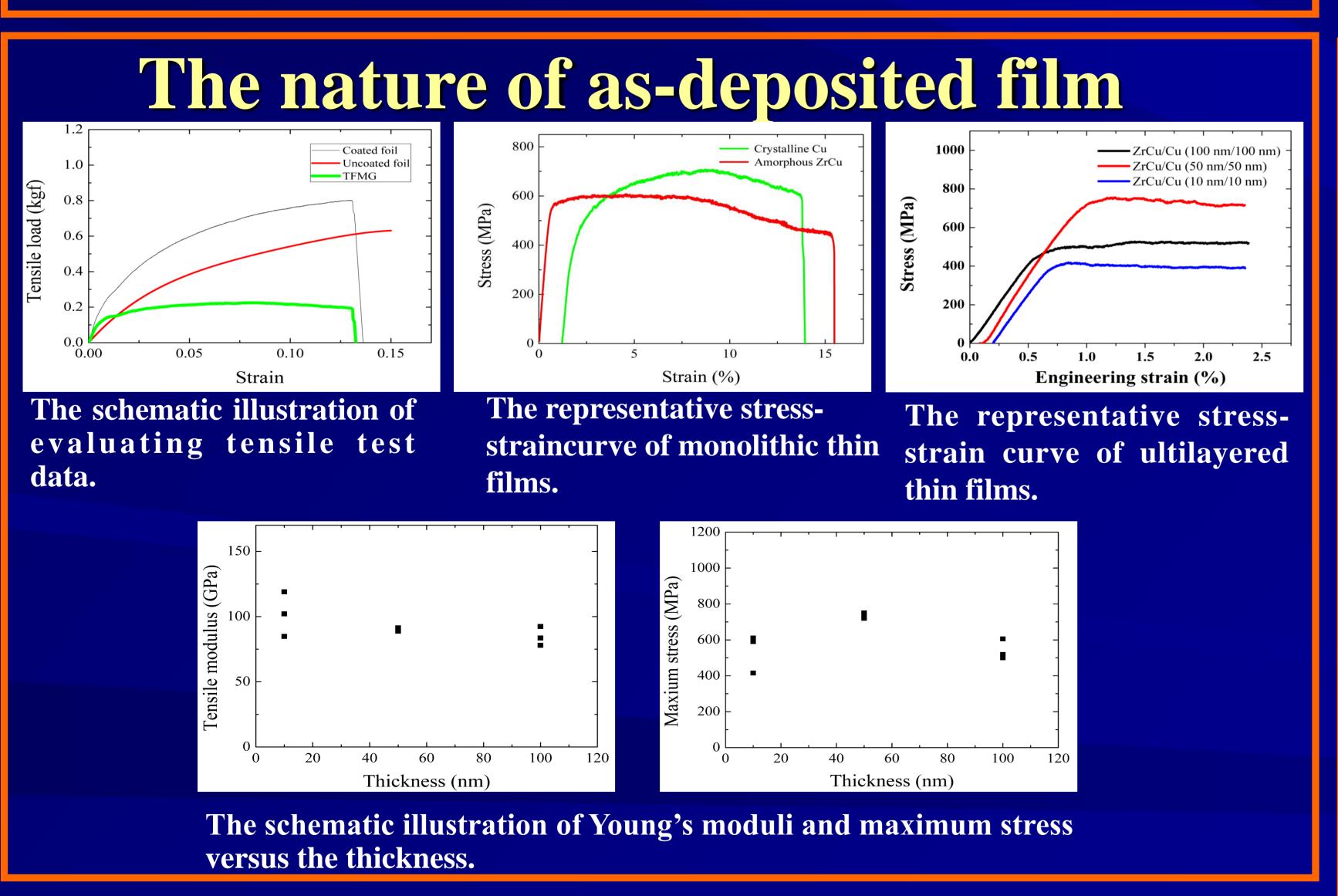
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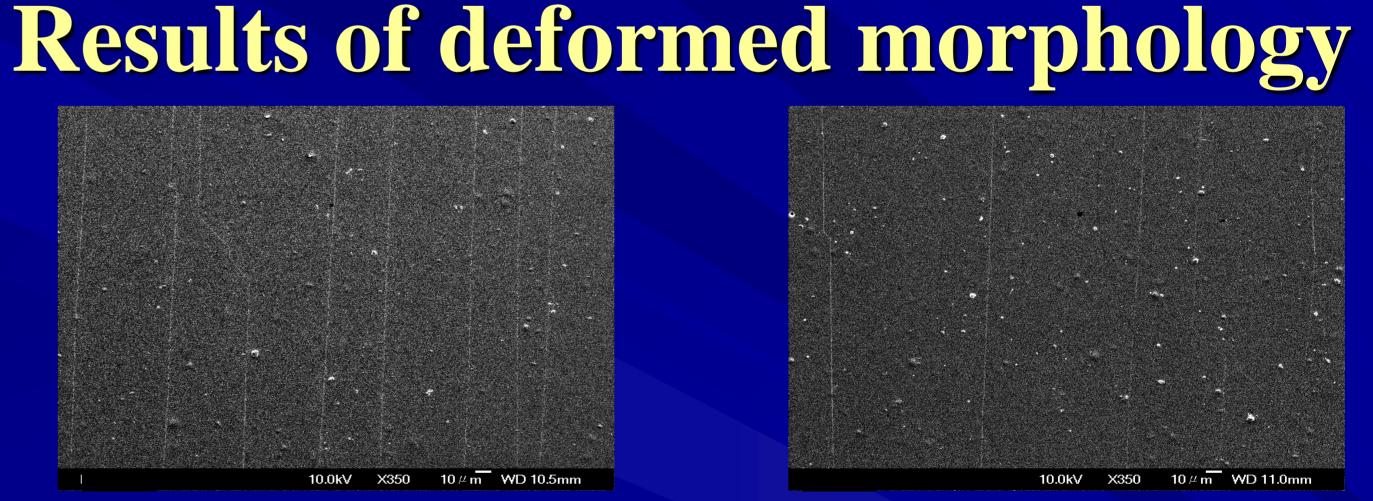
Abstract

The tensile behavior of the monolithic amorphous ZrCu and crystalline Cu thin films and the ZrCu/Cu multilayered thin films in different monolayer thicknesses has been investigated. The morphology of as-deposited thin film is composed of sphere domains, and between the domains would be stress-concentrated. The cracks vertical to the loading direction would propagate along the domains. The tensile moduli of monolithic amorphous ZrCu and crystalline Cu thin films are closed to results extracted from micro-compression. Based on the current results for the moduli of multilayered thin films obtained from the tensile tests, it is reliable and consistent with the theoretically rule of mixture prediction. As the monolayer thickness going down from 100 nm to 10 nm, the tensile moduli would not change too much. The ductility and maximum stress would be improved.

## Experimental procedures Cutting polyimide (50 µm) into suitable size Cleanning polymer substrate by ultrasonic cleaning in isopropanol for 5 minutes Sticking the polymer substrate on holder, then put on the 0.3-mm-thick 304 stainless mask Depositing ZrCu/Cu multi-layer at the thickness of 1 µm in different thickness ratio **Confirming the Examining the** Observing the mechanical property crystal structure by morphology by SEM by Mini-Tester **XRD**



## Examination of film properties ZrCu amorphous humb Amorphous ZrCu Cu(200) Crystalline Cu ZrCu/Cu (100 nm/100 nm) ZrCu/Cu (50 nm/50 nm) EDS pattern of the as-ZrCu/Cu (10 nm/10 nm) deposited amorphous Zr<sub>46</sub>Cu<sub>54</sub> thin film on the 2θ (deg) silcon nitride substrate. XRD pattern of the monolithic and multilayered thin films on the polyimide substrate.



SEM surface morphology of the undeformed ZrCu/ Cu (100

SEM surface morphology of the deformed ZrCu/Cu (100 nm/100 nm) multilayer sample

nm/100 nm) multilayer sample

10.0kV X350 10 μ m WD 11.0mm

SEM surface morphology of the deformed ZrCu/Cu (10 nm/10 nm) multilaver sample

SEM surface morphology of the deformed ZrCu/Cu (50 nm/50 nm) multilayer sample

The schematic illustration of crack distances of the deformed thin films

## Conclusions

From the SEM surface morphology observation, the as-deposited thin film is smooth under low magnification, but the sphere domains can also be observed under high magnification. XRD analysis shows the multilayered thin films are composed of amorphous and crystalline metals. The tensile moduli of monolithic amorphous ZrCu and crystalline Cu thin films are close to results from nano-compression, and the multilayered thin films deducting the fitted PI curve agree well with the theoretically rule of mixture prediction. The current study demonstrates that the nanolaminate of ZrCu/Cu (50/50 nm) can reach the highest maximum stress among all samples. Besides, There is no much difference in the moduli dustility under the varient thickness condititions.